

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of: **OZAKI, Takashi, et al.**

Group Art Unit: **1792**

Serial No.: **10/528,137**

Examiner: **MACARTHUR, Sylvia**

Filed: **December 12, 2005**

P.T.O. Confirmation No.: **2307**

**FOR: SUBSTRATE PROCESSING APPARATUS AND METHOD FOR
MANUFACTURING A SEMICONDUCTOR DEVICE**

RESPONSE UNDER 37 CFR §1.116

**- EXPEDITED RESPONSE -
GROUP ART UNIT 1792**

MAILSTOP AF

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

February 4, 2010

Sir:

In response to the Final Office Action dated **November 13, 2009**, please amend the above-identified application as follows:

Amendments to the Claims are reflected in the listing of claims which begins on page 2 of this paper.

Remarks/Arguments begin on page 12 of this paper.